FORM PTO-1449	SERIAL NO. To be Assigned	CASE NO. 7103/4000
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT	FILING DATE Herewith	GROUP ART UNIT 3723
(use several sheets if necessary)	APPLICANT: Alan J. Jensen et al.	

REFERENCE DESIGNATION **U.S. PATENT DOCUMENTS**

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS/ SUBCLASS	FILING DATE
	A1	3,753,269	08/21/73	Budman		
	A2	4,318,250	03/09/82	Klievoneit et al.		
	A3	4,672,985	06/16/87	Mohr		
	A4	4,720,939	01/26/88	Simpson et al.		
	A5	4,934,102	06/19/90	Leach et al.		
	A6	5,081,051	01/14/92	Mattingly et al.		
	A7	5,335,453	08/09/94	Baldy et al.		
	A8	5,484,323	01/16/96	Smith		
	A9	5,527,424	06/1996	Mullins		
	A10	5,531,635	07/02/96	Mogi et al.		
	A11	5,536,202	7/16/96	Appel et al.		
	A12	5,547,417	08/20/96	Breivogel et al.		
	A13	5,558,568	09/24/96	Talieh et al.		
	A14	5,575,707	11/19/96	Talieh et al.		
	A15	5,593,344	01/14/97	Weldon et al.		
	A16	5,611,943	03/18/97	Cadien et al.		
	A17	5,622,526	04/22/97	Phillips		
	A18	5,643,044	07/01/97	Lund		
	A19	5,655,951	08/12/97	Meikle et al.		
	A20	5,692,947	12/02/97	Talieh et al.		
	A21	5,692,950	12/02/97	Rutherford et al.		
	A22	5,708,506	01/1998	Birang		
	A23	5,725,417	03/10/98	Robinson		
	A24	5,759,918	06/02/98	Hoshizaki et al.		
	A25	5,762,536	06/09/98	Pant et al.		
	A26	5,779,526	07/14/98	Gill		
	A27	5,871,390	02/16/99	Pant et al.		
	A28	5,897,426	04/27/99	Somekh		
	A29	5,899,798	05/04/99	Trojan et al.		
	A30	5,908,530	06/01/99	Hoshizaki et al.		
	A31	5,941,761	08/1999	Nagahara et al.		
	A32	5,958,794	09/28/99	Bruxvoort et al.		
	A33	5,990,010	11/1999	Berman		
	A34	6,086,460	07/11/00	Labunsky et al.		
	A35	2001/0015801 A1	08/23/01	Hirose et al.		
	A36	6,273,798 B1	08/2001	Berman		

EXAMINER	DATE CONSIDERED 01/03/05

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FORM PTO-1449	SERIAL NO. To be Assigned	CASE NO. 7103/400
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT	FILING DATE Herewith	GROUP ART UNIT 3723
(use several sheets if necessary)	APPLICANT(S): A. Jensen	

REFERENCE DESIGNATION **U.S. PATENT DOCUMENTS**

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS/ SUBCLASS	FILING DATE
JST	A37	6,300,247 B2	10/2001	Prabhu		
	A38	6,306,019	10/23/01	Finkelman		
	A39	6,309,277 B1	10/2001	Arcayan et al.		
	A40	6,328,637	12/11/01	Labunsky et al.		
	A41	6,361,409 B1	03/2002	Vishwanathan et al.		
	A42	6,361,414	03/26/02	Ravkin et al.		
	A43	6,395,194 B1	05/2002	Russell et al.		
	A44	6,413,135 B1	07/2002	Pinson et al.		
JST	A45	6,475,069 B1	11/2002	Thomas et al.		

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EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS/ SUBCLASS	TRANSLATION YES	NO
JST	A46	WO 98/45090	10/15/98	PCT			
	A47	WO 99/22908	05/14/99	PCT			
JST	A48	WO 01/32360 A1	05/10/01	PCT			

EXAMINER INITIAL		OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)
JST	A49	S. Inaba, T. Katsuyama, M. Tanaka, "Study of CMP Polishing pad Control Method," 1998 CMP-MIC Conference, February 19-20, 1998, 1998 IMIC – 300P/98/0444.
	A50	U.S. Patent Application Serial No. 09/540,602: "METHOD AND APPARATUS FOR CONDITIONING A POLISHING PAD"; Inventor: John M. Boyd; Filed March 31, 2000; Attorney Docket No. 7103-133
JST	A51	U.S. Patent Application Serial No. 09/607,743: "A CONDITIONING MECHANISM IN A CHEMICAL MECHANICAL POLISHING APPARATUS FOR SEMICONDUCTOR WAFERS"; Inventors: Vogtmann et al.; Filed June 30, 2000; Attorney Docket No. 7103-173
JST	A52	Copy of International Search Report for PCT/US02/31924 dated January 20, 2003.

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FORM PTO-1449	SERIAL NO. 10/678,727	CASE NO. 7103/400
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT	FILING DATE October 3, 2003	GROUP ART UNIT 3723
(use several sheets if necessary)	APPLICANT(S): A. Jensen et al.	

EXAMINER INITIAL	OTHER ART – NON PATENT LITERATURE DOCUMENTS (Include name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.	
BJT	B1	Copy of pending U.S. Patent Application Serial No. 10/100,740 entitled "Method And Apparatus For Conditioning Fixed-Abrasive Polishing Pads", filed March 19, 2002.

EXAMINER	DATE CONSIDERED
	01/03/05

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